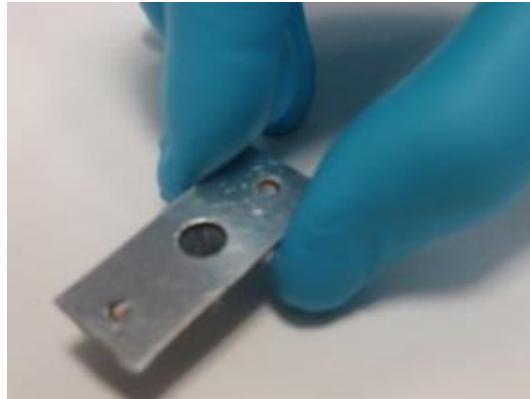
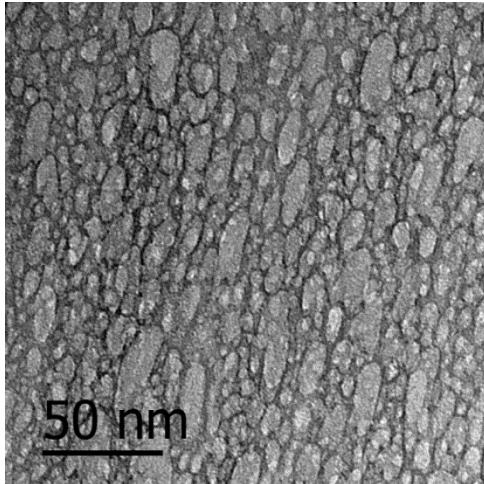


Solid targets containing high amount of ^4He for Nuclear Physics Experiments

F.J. Ferrer, B. Fernández, V. Godinho, J.P. Fernández-García,
A. Fernández, D. Galaviz, J. Gómez-Camacho



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- Team
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- Example 1: $^4\text{He}(^1\text{H}, ^1\text{H})$ ^4He Elastic scattering (Backscattering, $\theta > 90^\circ$)
- Example 2: $^4\text{He}(^6\text{Li}, ^6\text{Li})$ ^4He Elastic scattering (Forward scattering, $\theta < 90^\circ$)
- Perspectives: Next future
- Some bibliography

TEAM



Laboratory for Nanostructured Materials and Microstructure

- Dr. Vanda Godinho
- Dr. D Hufschmidt
- Dr. M.C. Jiménez de Haro
- Prof. Asunción Fernández

- Material synthesis (Magnetron sputtering)
- Morphological characterization (SEM, TEM)
- Elemental Characterization (EELS)

TEAM

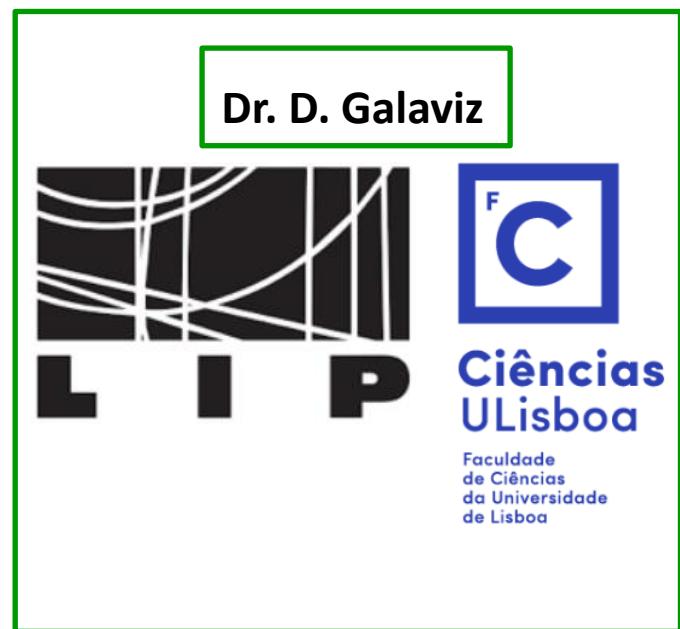


Centro Nacional de Aceleradores

- Dr. F. Javier Ferrer
- Dr. Begoña Fernández
- Dr. J.P. Fernández-García
- Prof. Joaquín Gómez

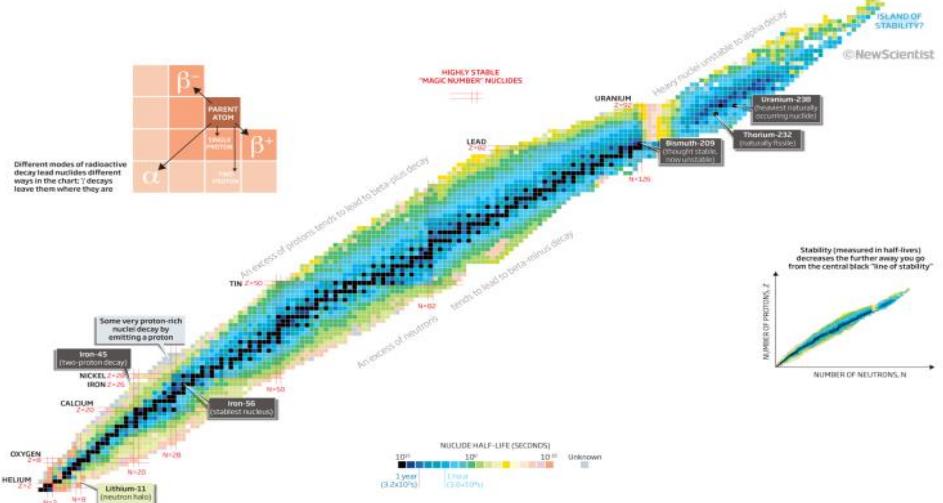
➤ Elemental characterization

➤ Nuclear Physics Experiments



➤ Nuclear Physics Experiments

GOAL



Using nuclear reactions for investigating properties of nuclei far from the stability line ("exotic" nuclei).

Protons	Alphas
$(^1\text{H}, ^1\text{H})$	Elastic scattering
$(^1\text{H}, ^3\text{H})$	Two neutron transfer
$(^1\text{H}, ^5\text{H})$	Four neutron transfer
	$(^4\text{He}, ^4\text{He})$
	$(^4\text{He}, ^6\text{He})$
	$(^4\text{He}, ^8\text{He})$

unstable exotic
nucleus



exotic nucleus = projectile
p or ^4He = target

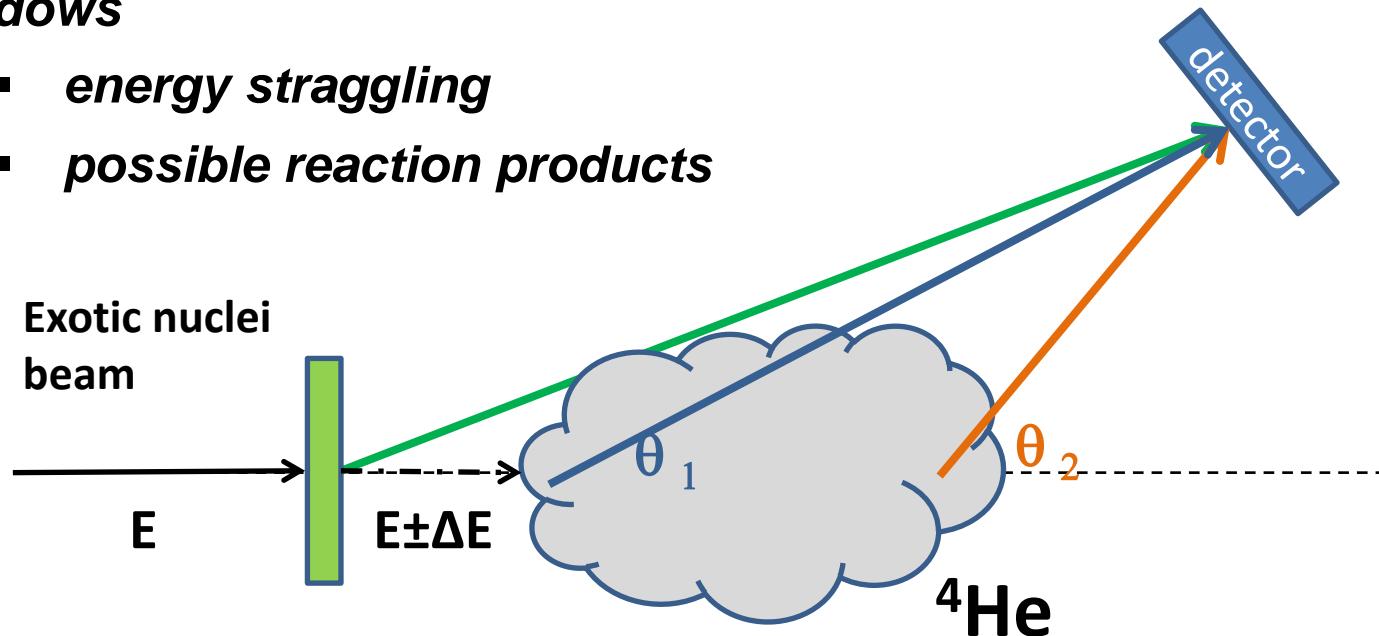
INVERSE
KINEMATIC

He filled chamber problems

Protons \longrightarrow polyethylene (CH_2)n
Alphas \longrightarrow GAS, no solid molecules

Problems:

- ***angular resolution***
- ***windows***
 - ***energy straggling***
 - ***possible reaction products***

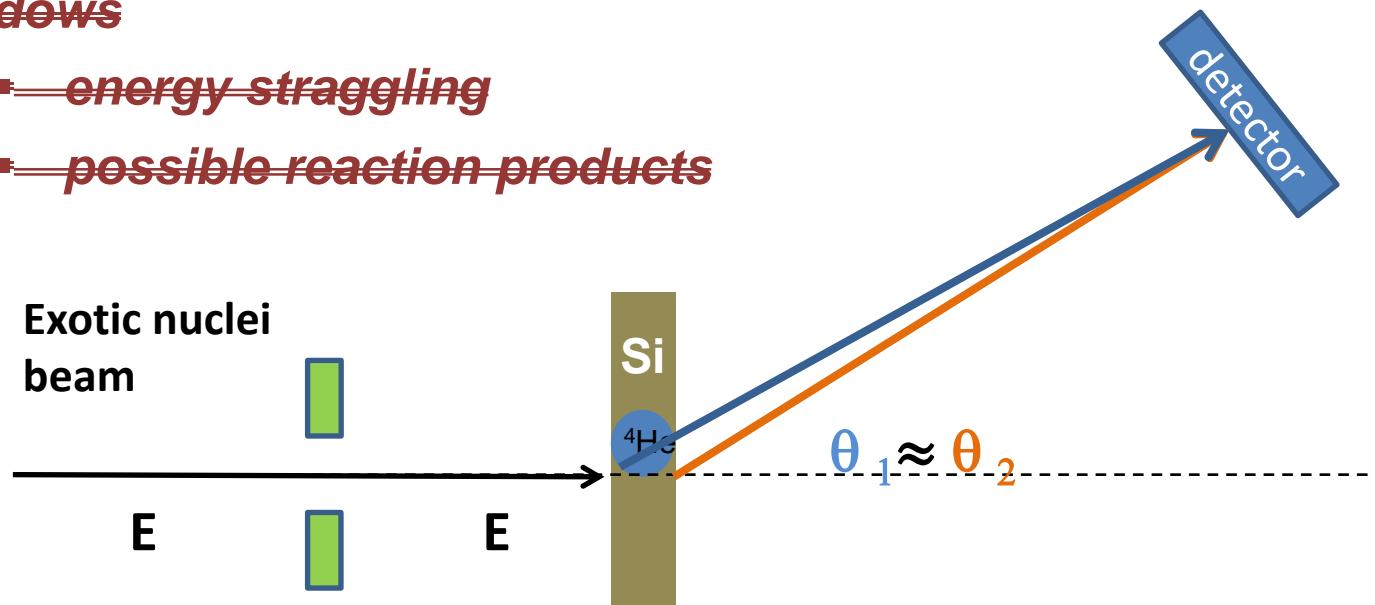


He solid targets solutions

Protons \longrightarrow polyethylene (CH_2)n
Alphas \longrightarrow GAS, no solid molecules

Problems:

- ~~angular resolution~~
- ~~windows~~
- ~~energy straggling~~
- ~~possible reaction products~~



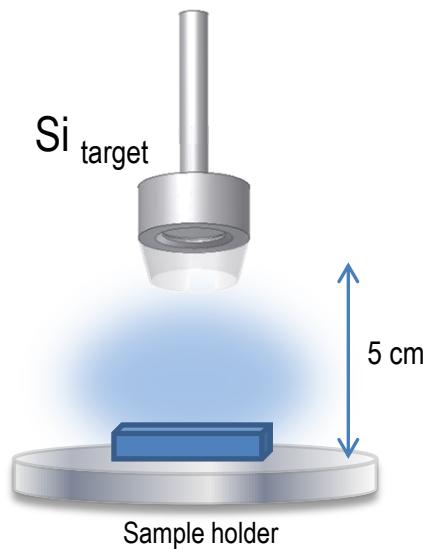
Implantation Alternative

Problems:

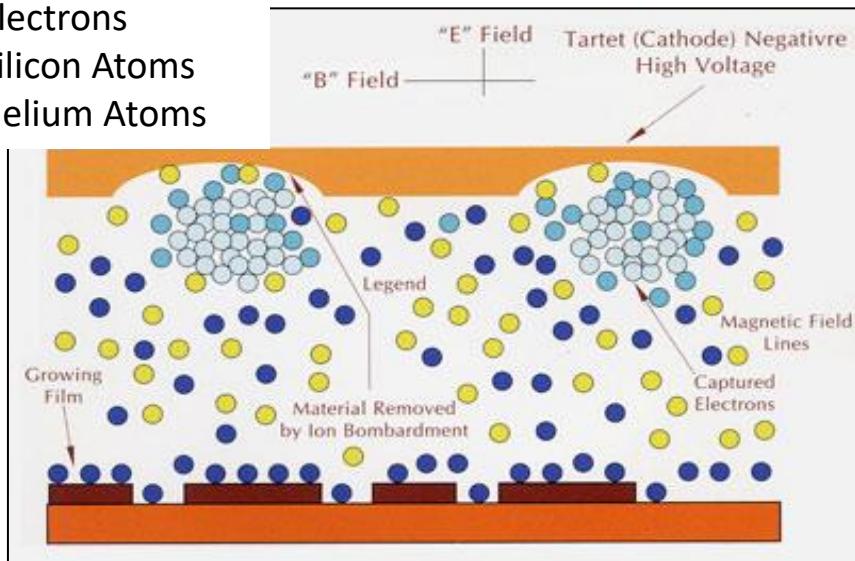
- ***Expensive use of implanter***
- ***Hardly achieved “homogeneous” profile***
- ***“Low” amount of ^4He***
- ***“High” (same order of ^4He) contamination (C, O)***

Sample preparation

Magnetron Sputtering



- Ions
- Electrons
- Silicon Atoms
- Helium Atoms



Adjustable parameters:

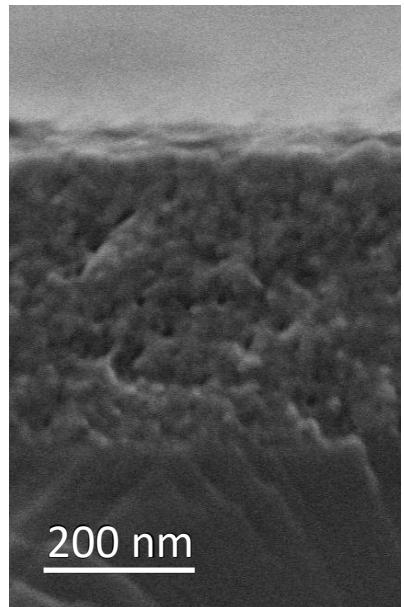
- RF/DC Power
- Substrate bias
- Gas type and Pressure
- Target material

Magnetron sputtering:

- Wide extended technique in industry
- Very versatile allowing to deposit on large areas
- Deposition on different kinds of substrates
- Controlling deposition parameters is possible to control the microstructure and composition

Morphological Characterization

SEM and TEM



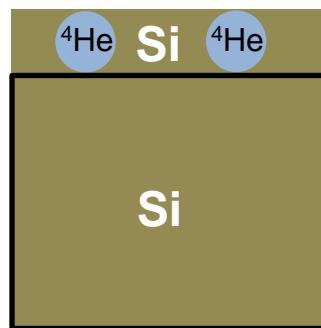
SEM
cross-setional view



TEM
cross-setional view

Control of porosity and ^4He amount inside the coating

➤ Homogeneously distributed pores structure

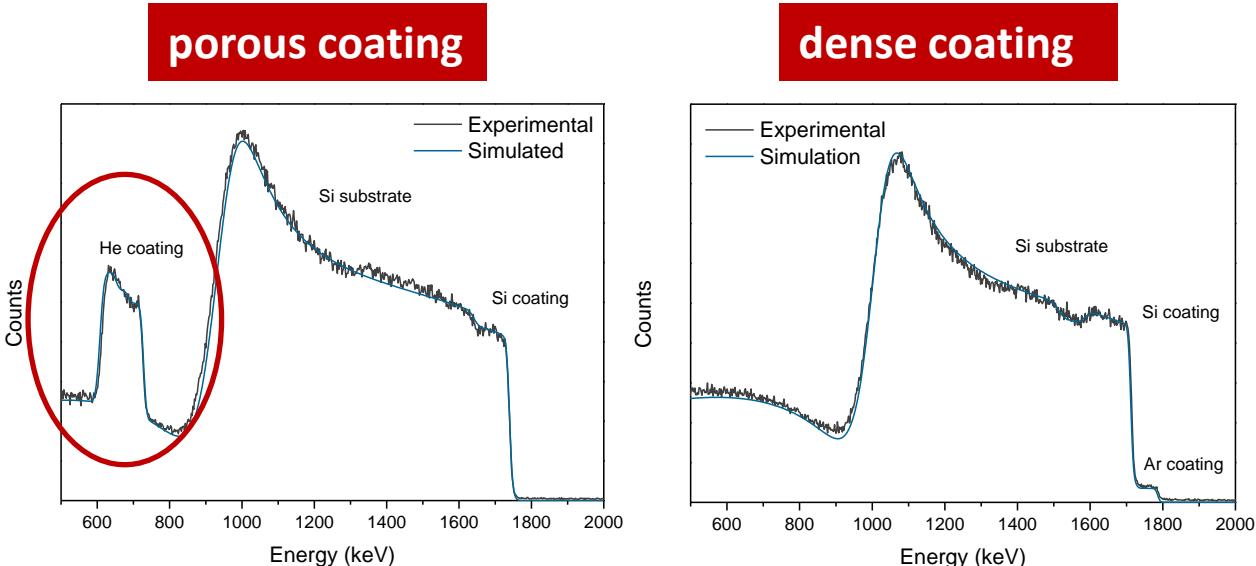
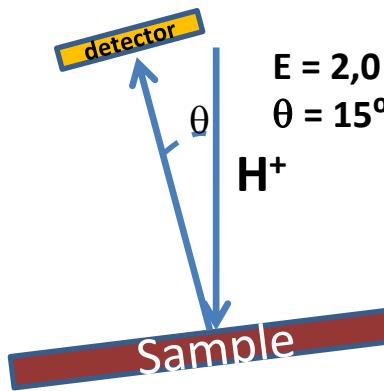


Control of parameters:

- RF/DC Power
- Substrate bias
- Gas type and Pressure
- Target material

Elemental Characterization

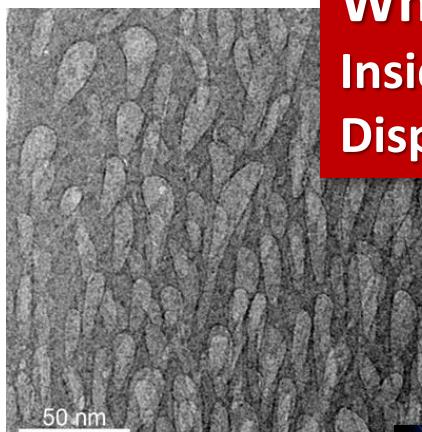
Elastic Backscattering Spectroscopy



Sample	thickness ($10^{15}\text{at}/\text{cm}^2$)	Si (%at)	^4He (%at)	Ar (%at)
porous	11000	78.7	21.3	--
dense	9500	92.0	--	6.0

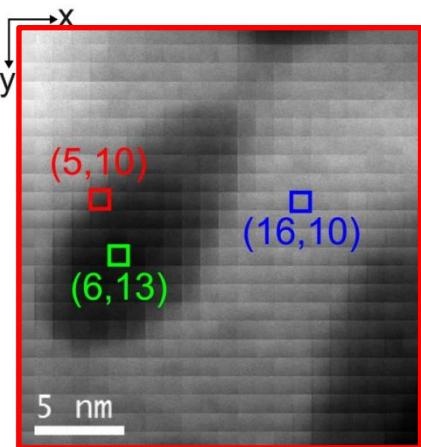
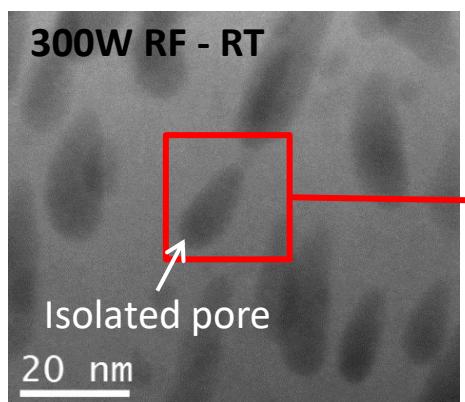
High amount of $^4\text{He}!!!$
 $^4\text{He/Si} = 0,27$

Where is ^4He ?
 Inside the pores?
 Dispersed?



Elemental Characterization

EELS (electron energy loss spectroscopy)



He localization and quantification at the nanoscale in porous Si

STEM-HAADF (Z-contrast)

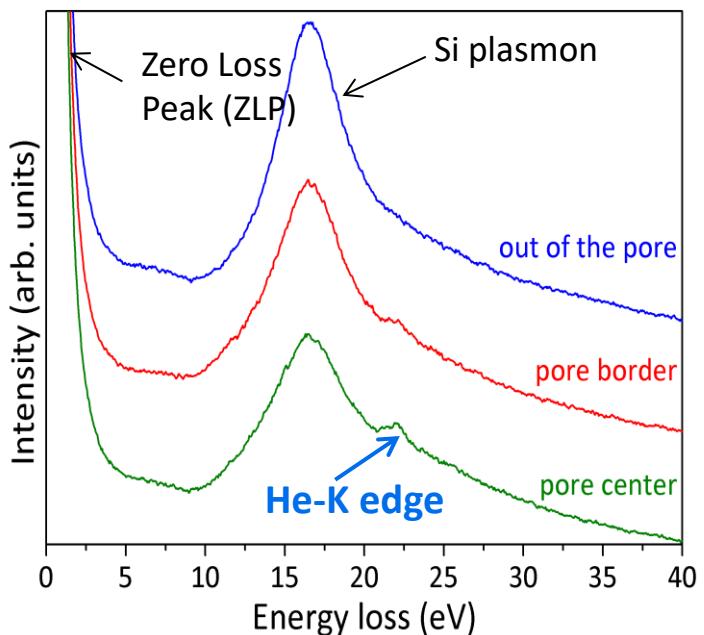
Intensity proportional to Z^2

Pores are darker than the matrix

Spectrum image dataset:

Pixel size: 1nm

Each pixel contains one EELS spectrum



EELS acquired in the Low Loss region

In the pore region:
additional peak around 22 eV → He-K edge

Helium localized inside the pores

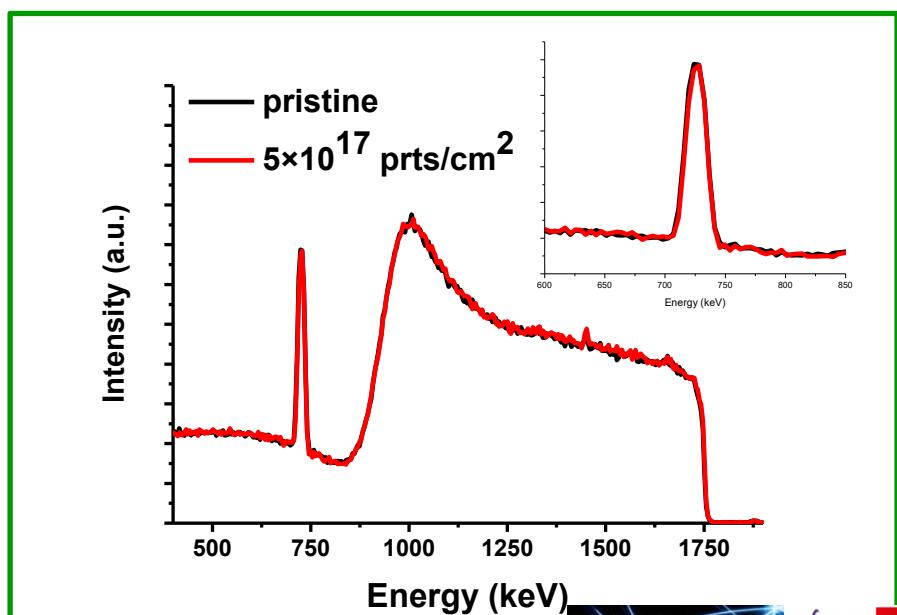
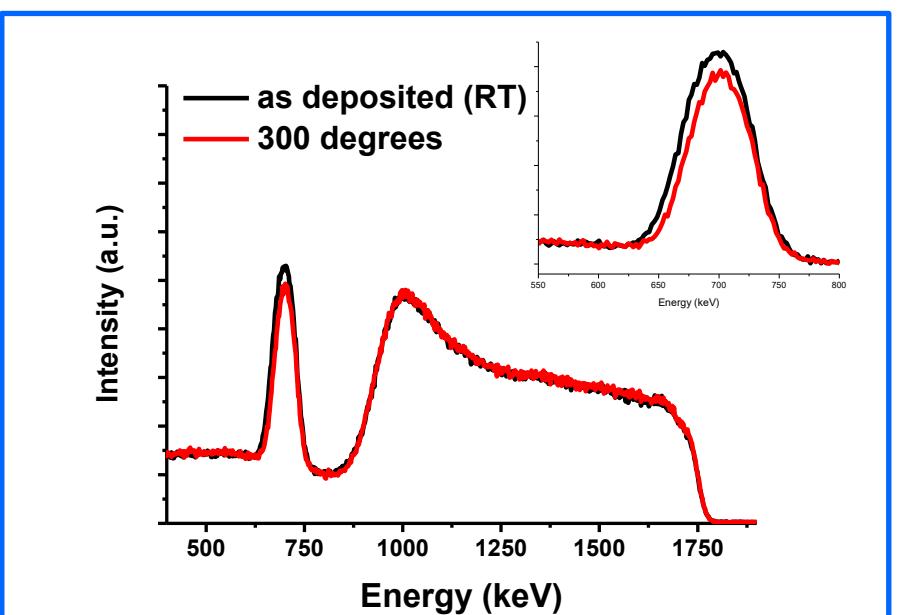
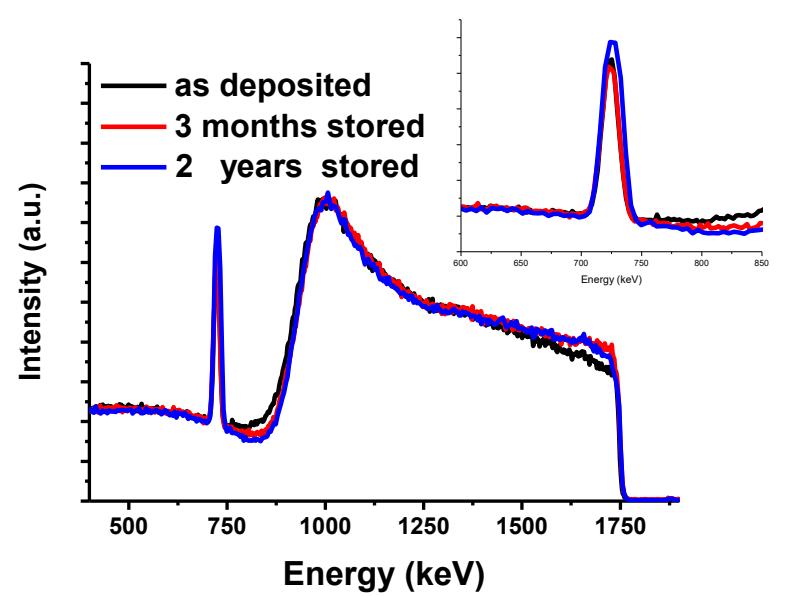
R. Schierholz et al, Nanotechnology 26 (2015) 075703

Stability of the targets

➤ Temperature

➤ Radiation

➤ Aging

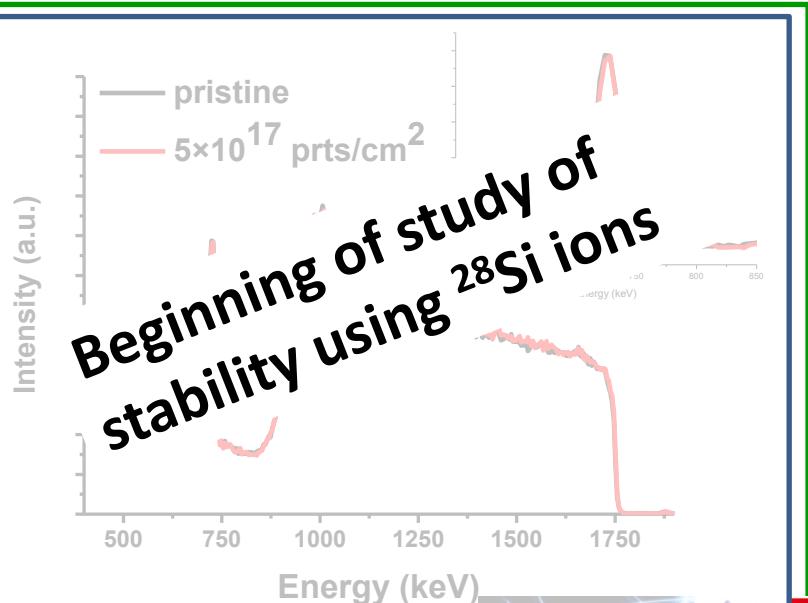
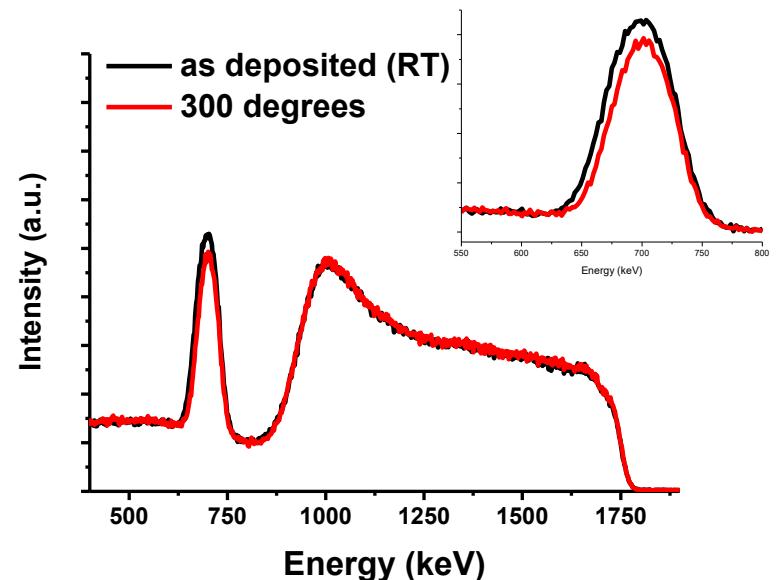
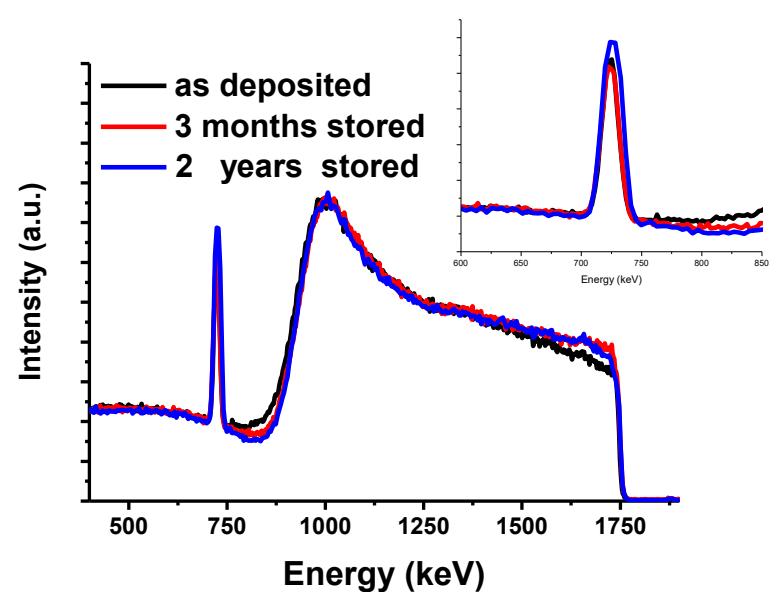


Stability of the targets

➤ Temperature

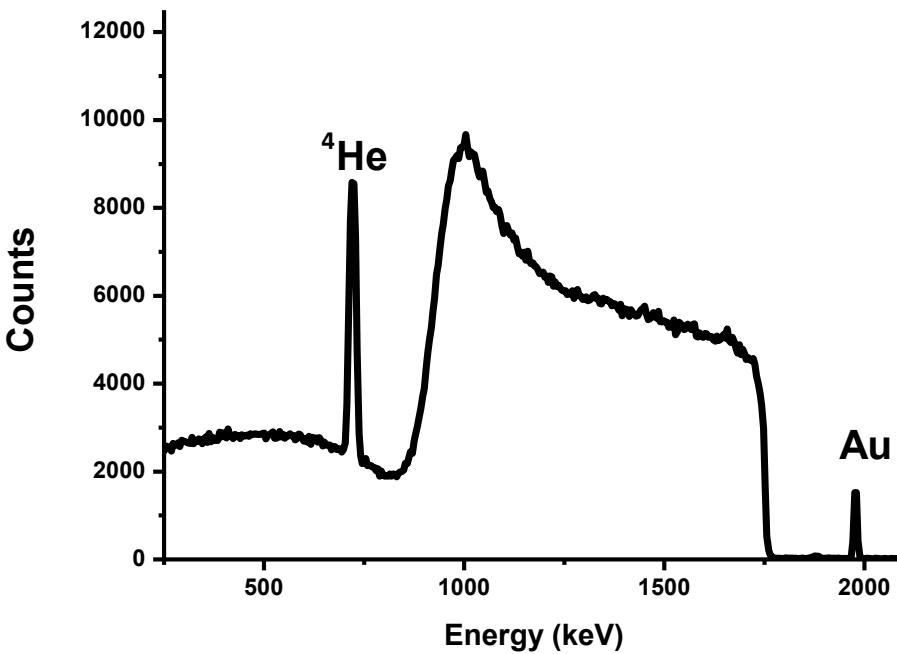
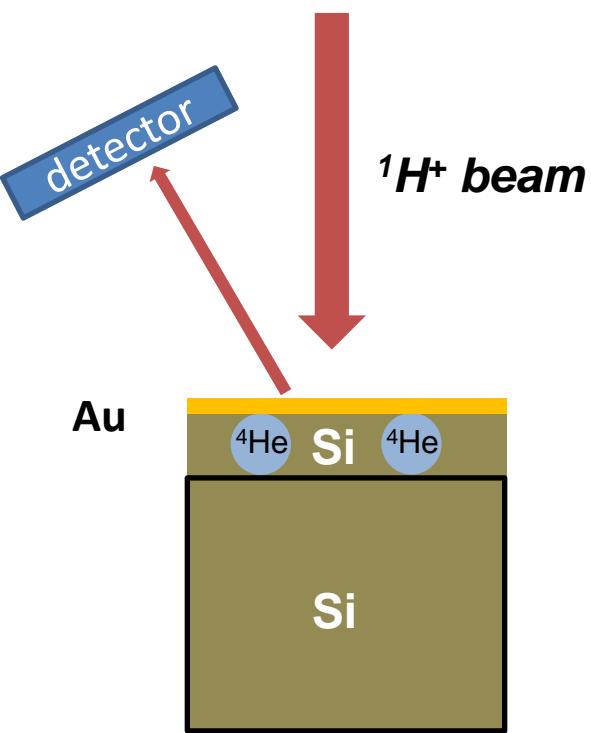
➤ Radiation

➤ Aging



Example 1: $^4\text{He}(^1\text{H}, ^1\text{H}) ^4\text{He}$ Elastic scattering**Backscattering ($\theta > 90^\circ$)**

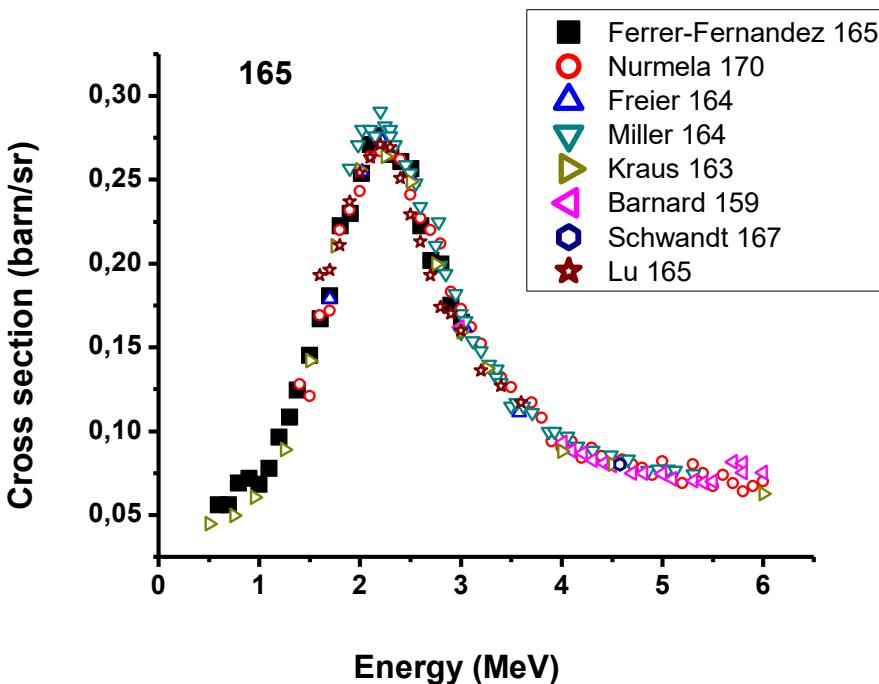
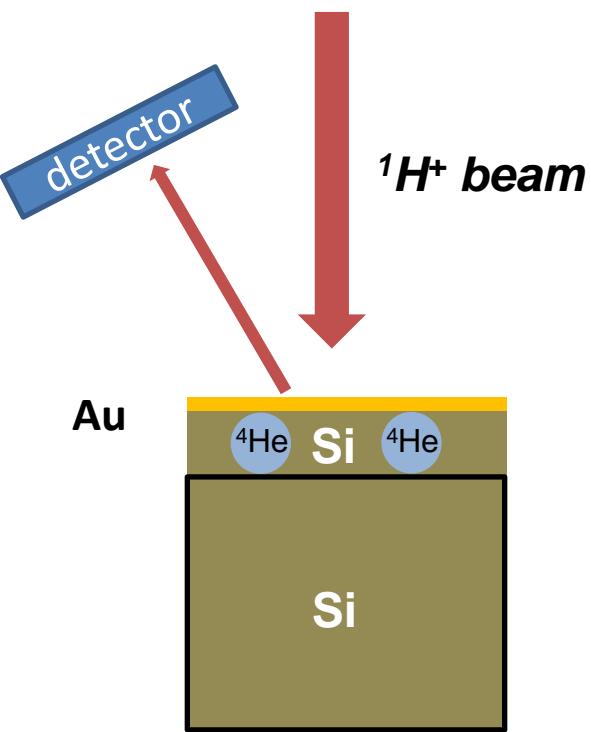
Si: $1000 \times 10^{15} \text{ at/cm}^2$
 ^4He : $550 \times 10^{15} \text{ at/cm}^2$



$$\frac{d\sigma}{dE_{He}}(E, \theta) = \frac{d\sigma}{dE_{Au, Ruth}}(E_0, \theta) \cdot \left(\frac{A_{He}}{A_{Au}}\right) \cdot \left(\frac{Nt_{Au}}{Nt_{He}}\right)$$

Example 1: $^4\text{He}(^1\text{H}, ^1\text{H}) ^4\text{He}$ Elastic scattering**Backscattering ($\theta > 90^\circ$)**

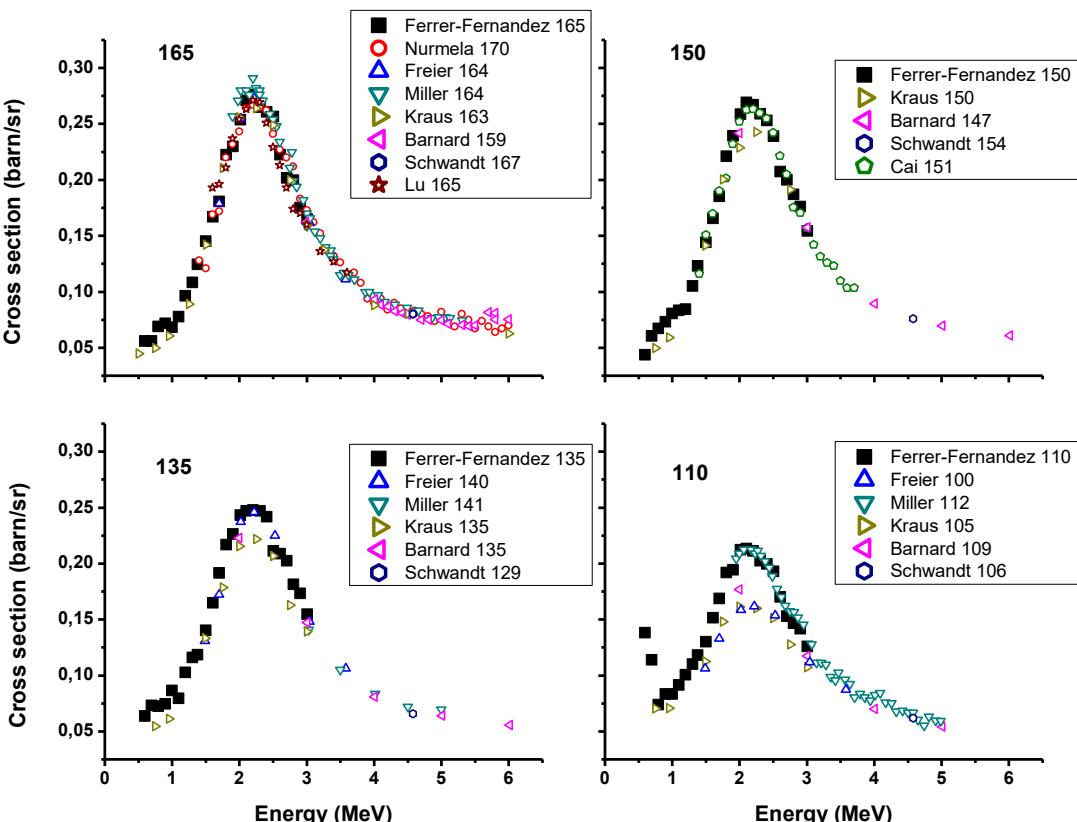
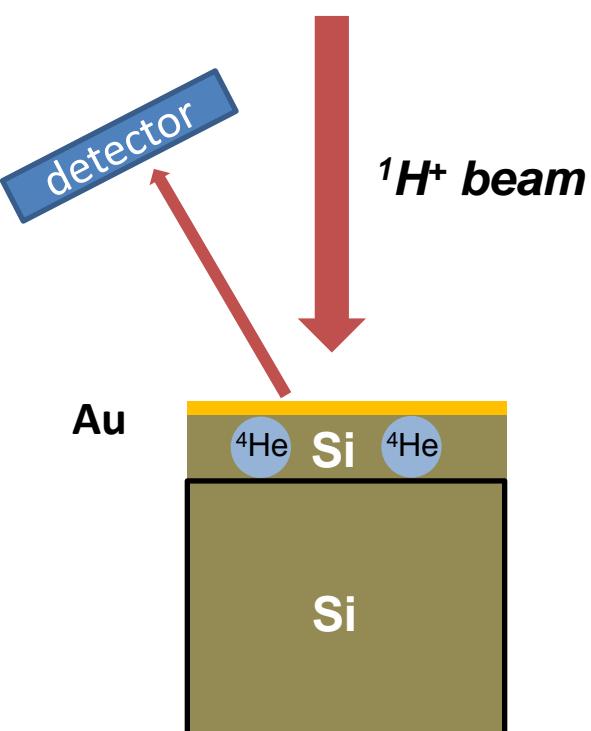
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Example 1: $^4\text{He}(^1\text{H}, ^1\text{H}) ^4\text{He}$ Elastic scattering**Backscattering ($\theta > 90^\circ$)**

Si: 1000×10^{15} at/cm 2
 He: 550×10^{15} at/cm 2

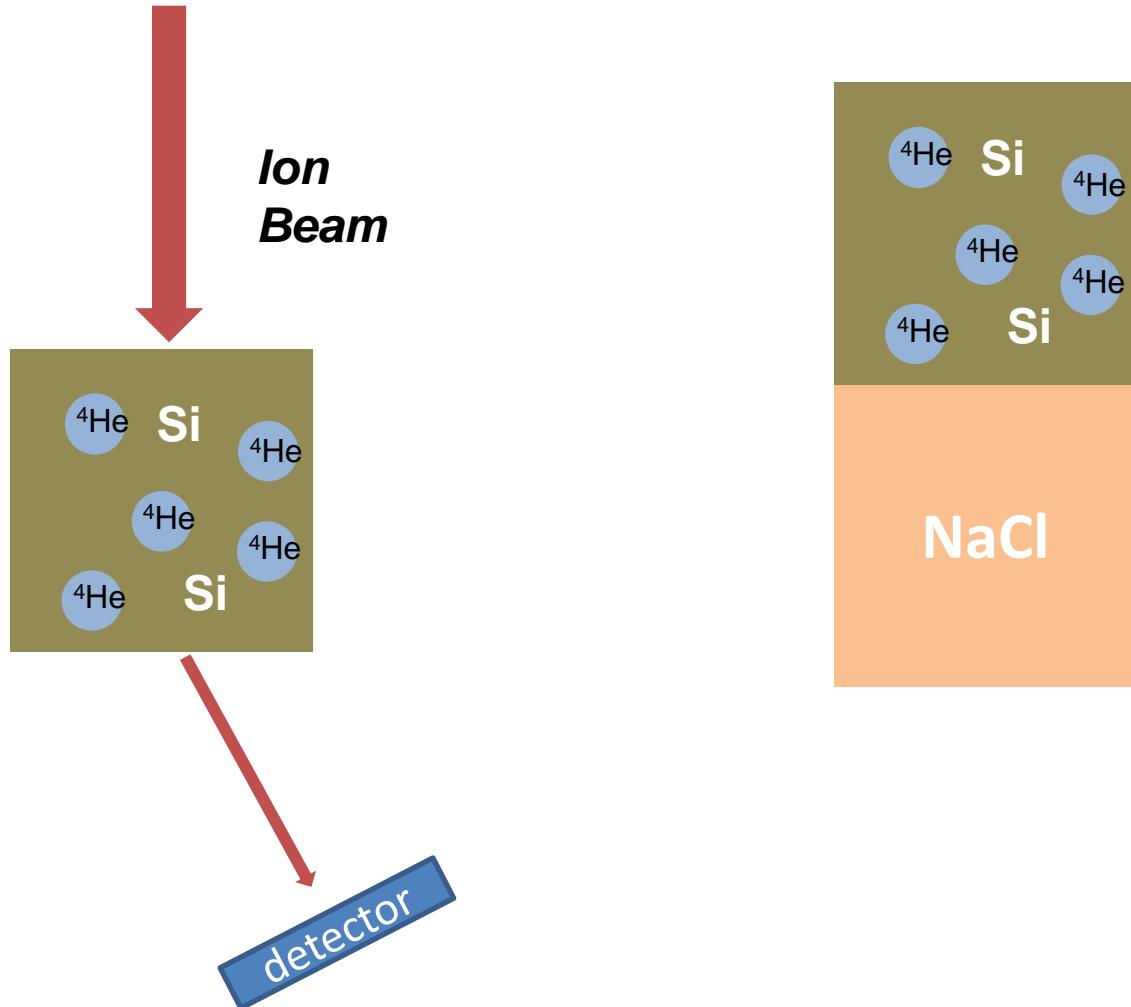


$^4\text{He}(^1\text{H}, ^1\text{H}) ^4\text{He}$ elastic scattering cross section included at Ion Beam Analysis Nuclear Data Library (IBANDL) and Experimental Nuclear Reaction Data (Exfor) from International Atomic Energy Agency (IAEA)



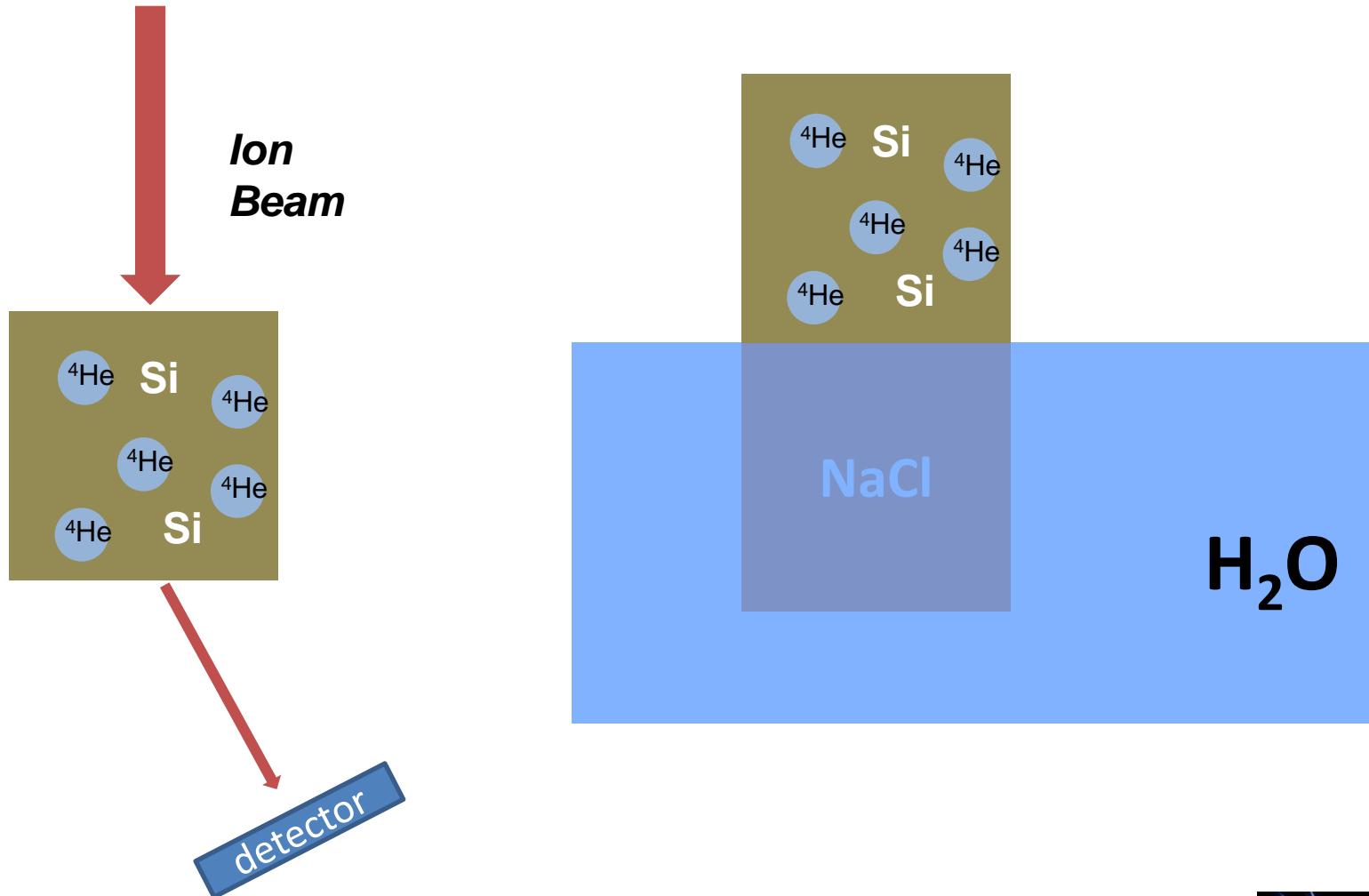
Example 2: $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering

Forward scattering ($\theta < 90^\circ$). Self-supported.



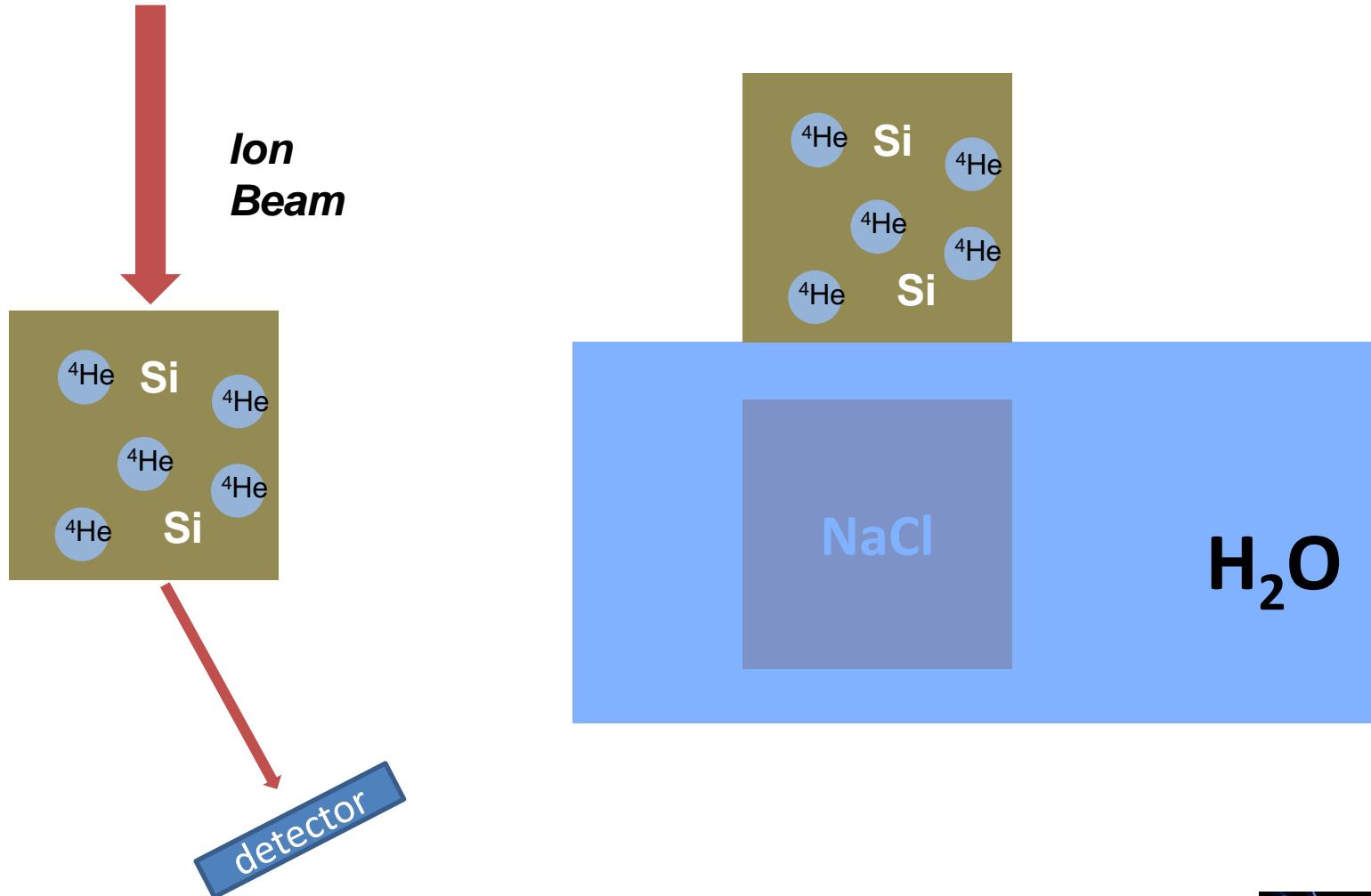
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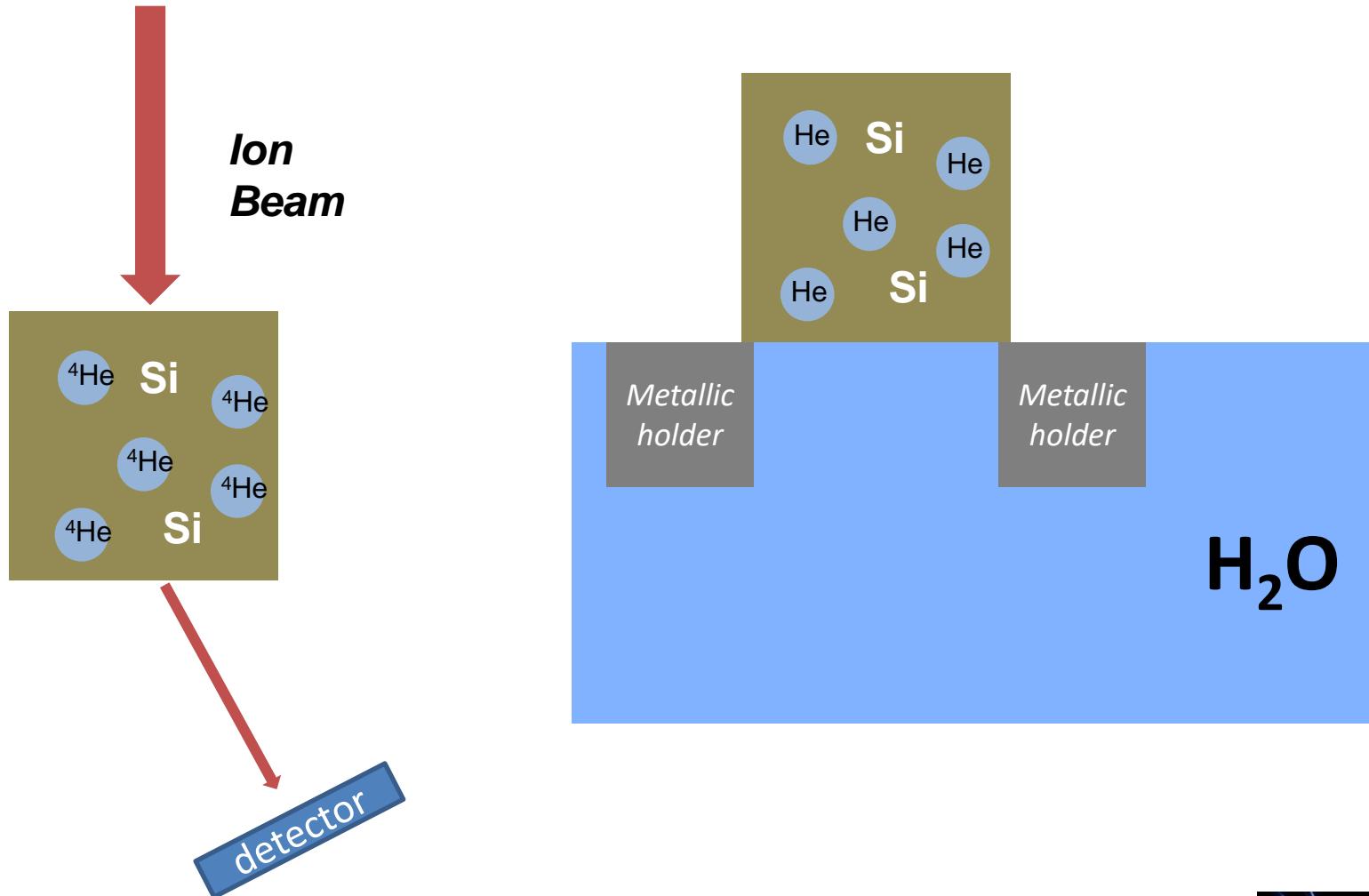
Forward scattering ($\theta < 90^\circ$). Self-supported.

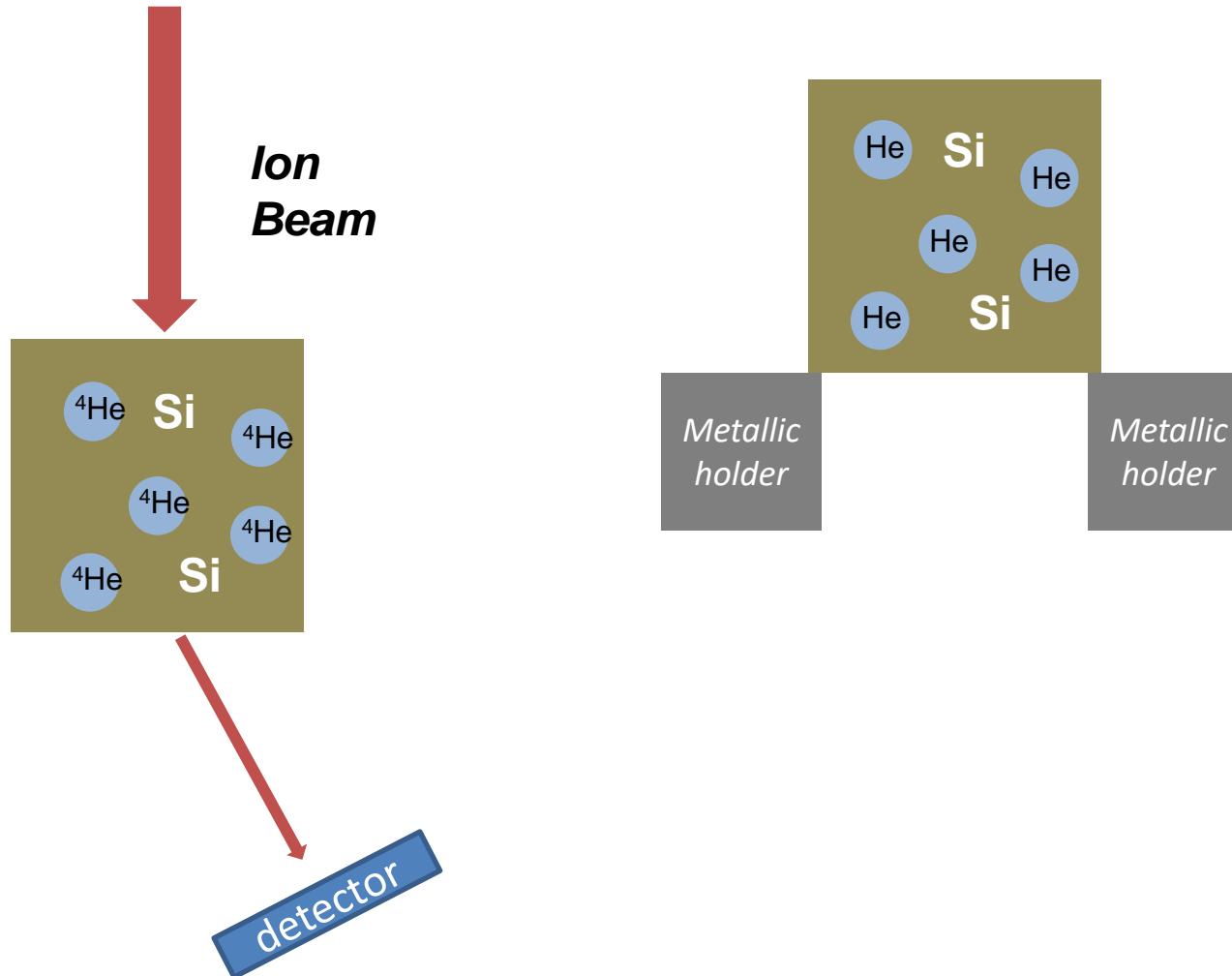


Example 2: $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering

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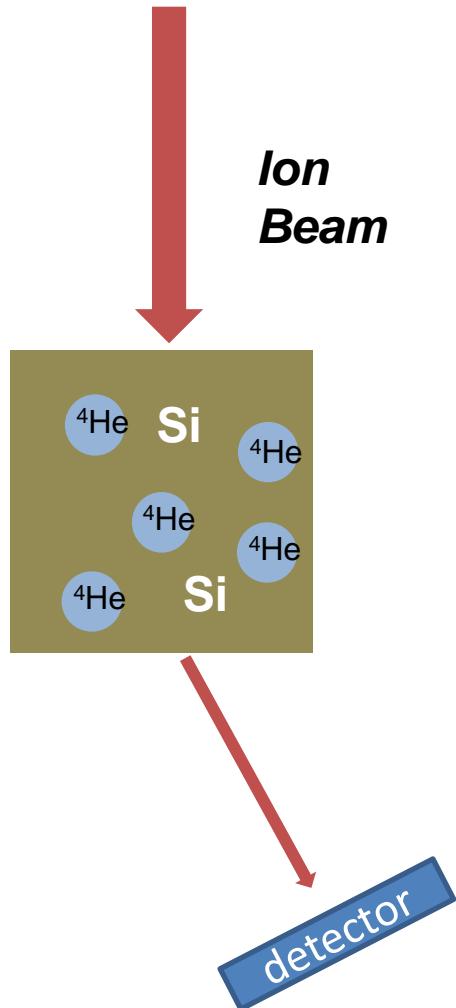


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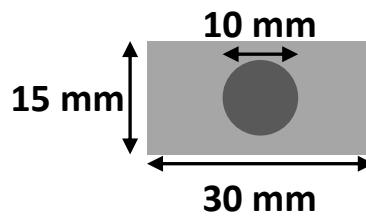
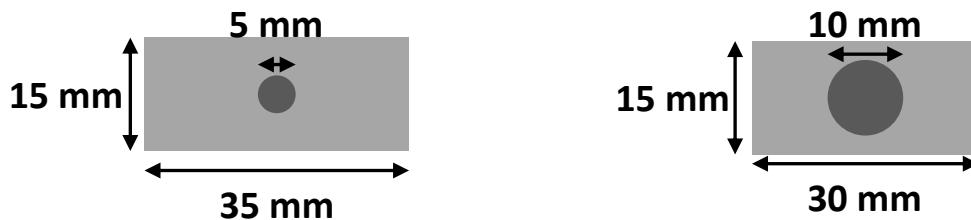
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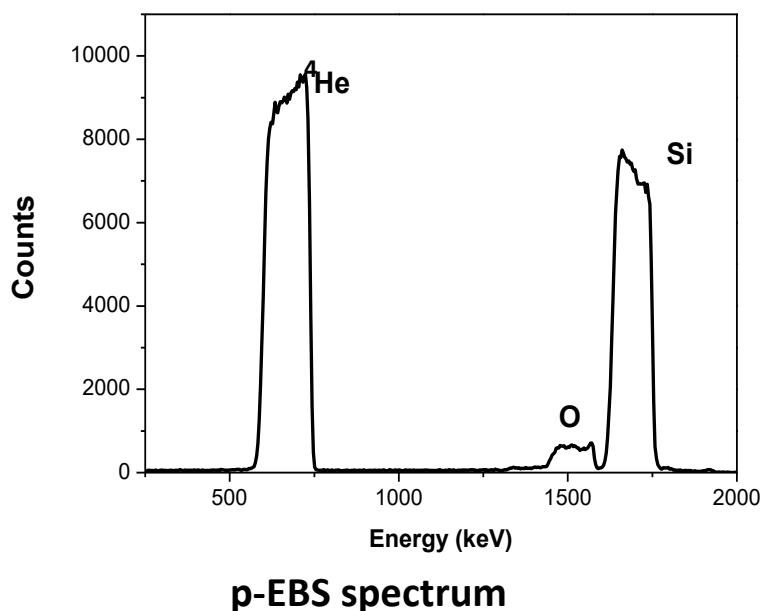
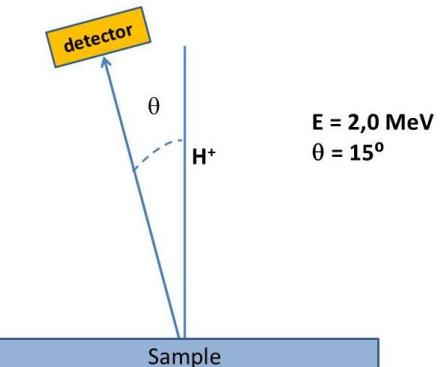
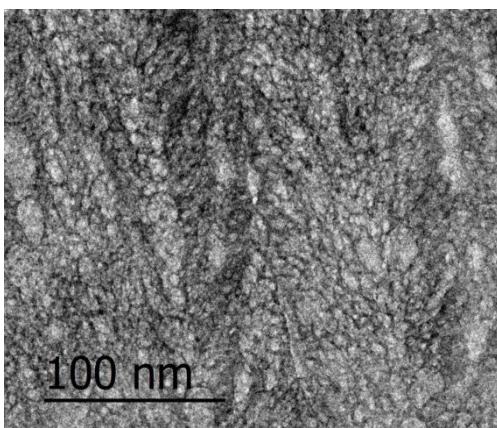
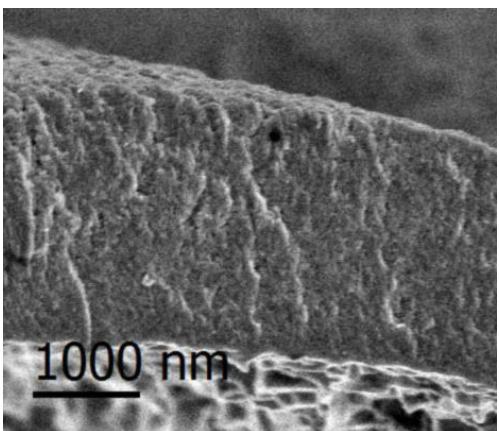
Example 2: $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering

Forward scattering ($\theta < 90^\circ$). Self-supported.



Self-supported Si: ^4He target



Example 2: $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering**Forward scattering ($\theta < 90^\circ$). Self-supported.****Self-supported porous a-Si: ^4He target**

Example 2: $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering**Forward scattering ($\theta < 90^\circ$). Self-supported.**

	Present work	Vanderbist et al. (2002)	Raabe et al. (2003)	Ujic et al. (2011)
Technique	Magnetron sputtering	Ion implantation	Ion implantation	Ion implantation
Metal ($\times 10^{15} \text{ at/cm}^2$)	(Si) 9250	(Al) 1100	(Al) 4200	(Al) 1200
^4He ($\times 10^{15} \text{ at/cm}^2$)	4060	275	270	130
O ($\times 10^{15} \text{ at/cm}^2$)	700	60	100	Not mentioned
$^4\text{He}/\text{M}$	0.44	0.25	0.06	0.11
O/He	0.17	0.22	0.37	Not mentioned

High amount of $^4\text{He}!!!$ **$^4\text{He}/\text{Si} = 0,44$**

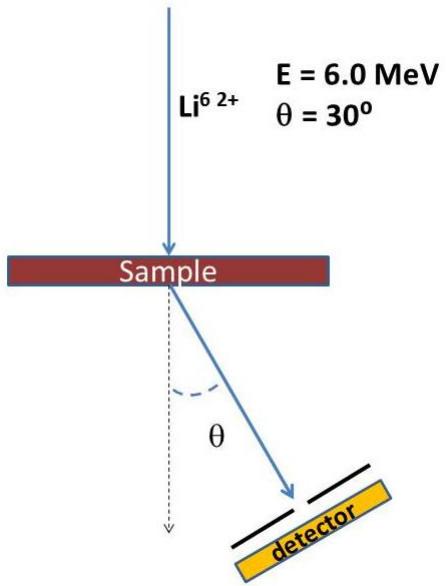
Example 2: $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering**Forward scattering ($\theta < 90^\circ$). Self-supported.**

	Present work	Vanderbist et al. (2002)	Raabe et al. (2003)	Ujic et al. (2011)
Technique	Magnetron sputtering	Ion implantation	Ion implantation	Ion implantation
Target (μm)	(Si) 2.3	(Al) 0.2	(Al) 0.7	(Al) 0.2
Metal ($\mu\text{g/cm}^2$)	430	50	200	50
^4He ($\mu\text{g/cm}^2$)	27	1.8	1.8	0.9
O ($\mu\text{g/cm}^2$)	19	1.6	2.7	Not mentioned

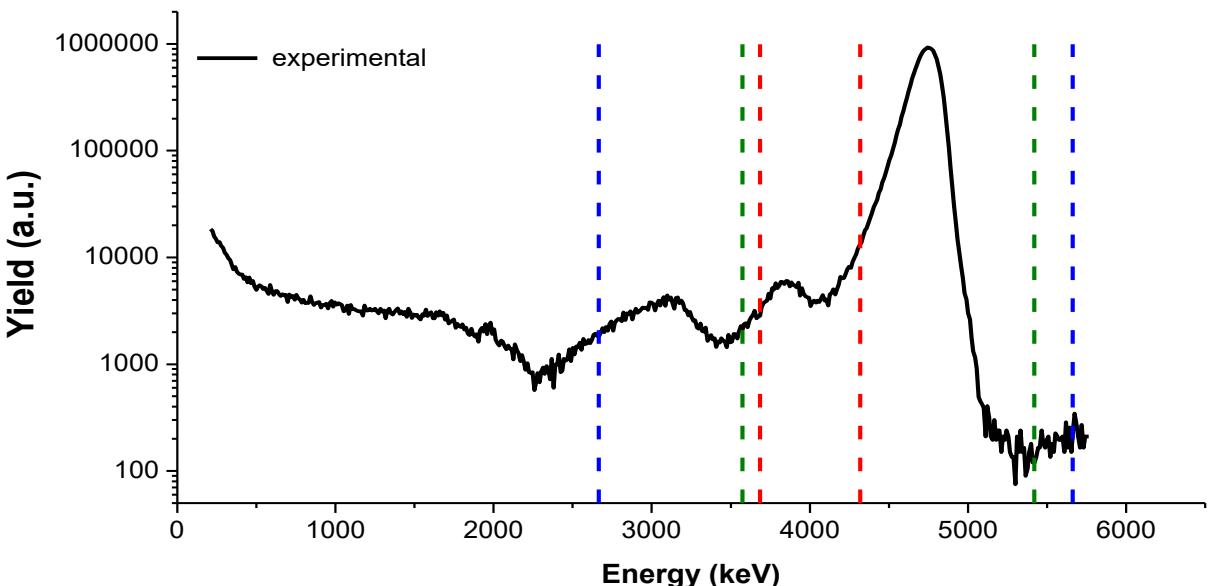
High amount of $^4\text{He}!!!$ **$^4\text{He/Si} = 0,44$**

Example 2: $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering**Forward scattering ($\theta < 90^\circ$). Self-supported.****□ $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering**

$$\begin{aligned} \text{Si: } 9250 \times 10^{15} \text{ at/cm}^2 &= 430 \mu\text{g/cm}^2 \\ \text{He: } 4060 \times 10^{15} \text{ at/cm}^2 &= 27 \mu\text{g/cm}^2 \\ \text{O: } 700 \times 10^{15} \text{ at/cm}^2 &= 19 \mu\text{g/cm}^2 \end{aligned}$$

**KINEMATICS**

$$\begin{aligned} \text{Li scattered by Si; Li (S Si)} &= 5664 \text{ keV} \\ \text{Si recoiled by Li; Si (R Li)} &= 2615 \text{ keV} \\ \text{Li scattered by } ^4\text{He; Li (S } ^4\text{He)} &= 3684 \text{ keV} \\ \text{ } ^4\text{He recoiled by Li; } ^4\text{He (R Li)} &= 4318 \text{ keV} \\ \text{Li scattered by O; Li (S O)} &= 5419 \text{ keV} \\ \text{O recoiled by Li; O (R Li)} &= 3574 \text{ keV} \end{aligned}$$

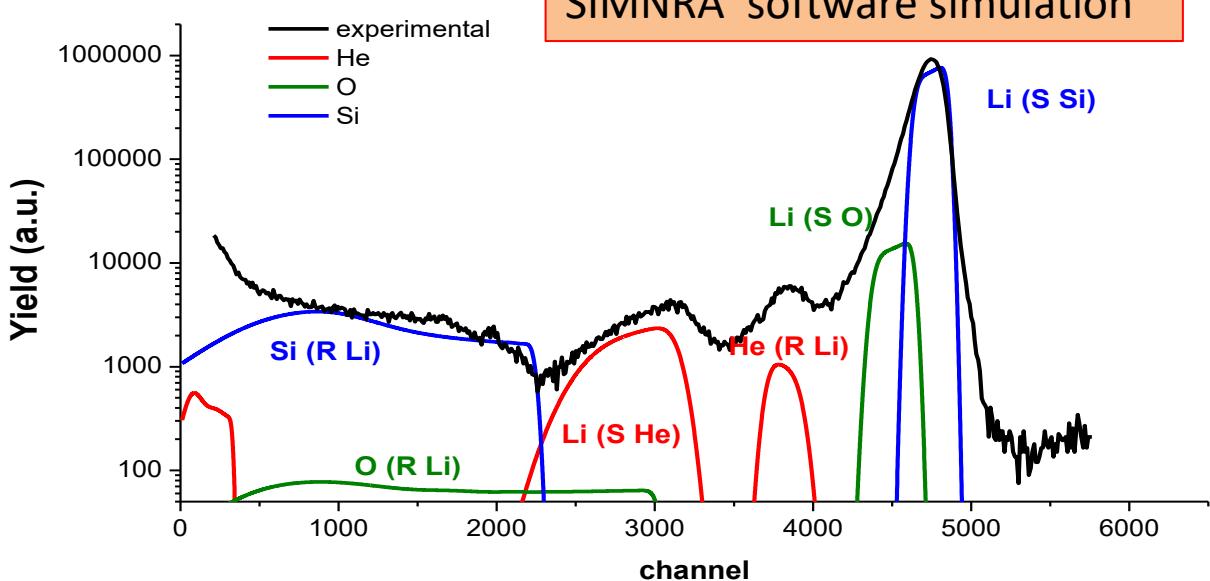
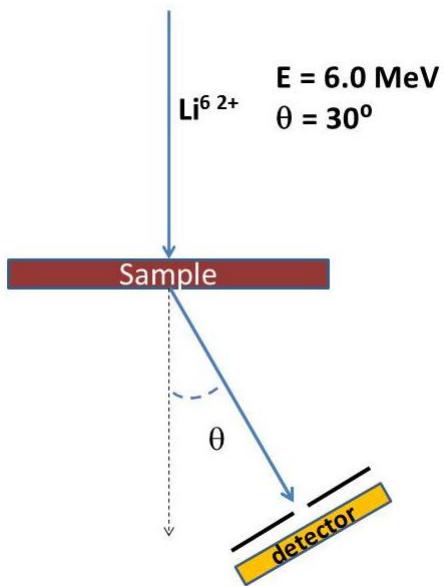


Example 2: $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering**Forward scattering ($\theta < 90^\circ$). Self-supported.****□ $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering**

Si: $9250 \times 10^{15} \text{ at/cm}^2 = 430 \mu\text{g/cm}^2$
$^4\text{He}: 4060 \times 10^{15} \text{ at/cm}^2 = 27 \mu\text{g/cm}^2$
O: $700 \times 10^{15} \text{ at/cm}^2 = 19 \mu\text{g/cm}^2$



***Stopping power
In the sample!!!***



Example 2: $^4\text{He}(^6\text{Li}, ^6\text{Li})^4\text{He}$ Elastic scattering**Forward scattering ($\theta < 90^\circ$). Self-supported.**Si: $9250 \times 10^{15} \text{ at/cm}^2 = 430 \mu\text{g/cm}^2$ 

*Stopping power
In the sample!!!*

	uma	E0	Ef	FWHM	FWHM/Ef	$\Delta E/E0$	MeV/uma
6Li 6 MeV	6	6,00	5,32	0,04	0,008	0,11	1,0
12C 15 MeV	12	15,00	13,18	0,09	0,006	0,12	1,3
28Si 21 MeV	28	21,00	15,03	0,20	0,013	0,28	0,8
64Ni 196 MeV	64	196,00	182,79	0,41	0,002	0,07	3,1
150Gd 900 MeV	150	900,00	866,91	0,89	0,001	0,04	6,0

Conclusions

- MS to produce Si:He targets He trapped in closed porosity
 - with high He/Si low O/Si content
- He homogeneously distributed throughout the film thickness
- Control of the MS parameters => control of the He content and morphology
- Reproducibility of the targets
- Targets deposited over a variety of substrates
- Self-supported targets

Conclusions

- Stability against fluence, temperature and aging.
- Validity for calculation of the differential cross-section for the elastic scattering of proton-helium in the energy range from 0.6 to 3.0 MeV at laboratory angles from 110 to 165°
- Proofs in forward geometry using ^6Li beam and self-supported coatings
- He solid targets for experiments with radioactive beams at
LARGE FACILITIES

Perspectives: Next future

- nuclear reactions at low energy (close to the Coulomb barrier)

- Targets: solid He targets
- Stable Beams: ^4He , ^6Li , ^7Li , ^8Be , ^{10}B y ^{12}C
- Forward geometry
- ΔE -E telescope with Si detectors



- Verify the experimental setup

- Detection system
- Electronic and data acquisition system



- Optimization of targets: higher He/Si and lower O/Si ratio



- nuclear reactions

- Targets: solid He targets
- Exotic Beams: ^6He , ^8He , ^{11}Li , ^7Be , ^{11}Be , ^{10}C y ^{11}C

LARGE
FACILITIES

Some bibliography

Papers

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Thank you for your attention

